

1000 U.S. 10/026419
12/26/01
J-107
PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10026419	FILING DATE 12/26/2001	CLASS 430	SUBCLASS 322	GAU 1752	EXAMINER Chacko-Davis
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**CONTINUING DATA VERIFIED: *WD*

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** FOREIGN APPLICATIONS VERIFIED: *WD*

JAPAN 2000-394354 12/26/2000

JAPAN 2001-011299 01/19/2001

JAPAN 2001385349 12/19/2001

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO 04329.2718
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiner's initials <i>WD</i>		U.S. DEPT. OF COMM./PAT. & TM-PTO-433L (Rev. 12-94)	
TITLE : Apparatus for processing substrate and method of processing the same			

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims 0	Print Claim for 0.0
Assistant Examiner		DRAWING	
		Sheets Drawn 0	Fig.s Drawn 0
Primary Examiner		Print FIG.	
PREPARED FOR ISSUE		Application Examiner	
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